

INVERTED METALLURGICAL MICROSCOPES

MODELS **PME · PMD · MG · MGK**



Olympus TOKYO

MODEL PME



SPECIFICATIONS

- 1. STAND**—Unique, stable, well balanced design and wear-resistant Olympus gray finish. With viewing screen.
- 2. INCLINED BINOCULAR BODY** (30 degrees from horizontal) for either observation or 35 mm camera photography.
- 3. OPTICS**—Four coated, flat field, parfocal achromatic objectives on revolving nosepiece:

M5X (N.A. 0.10)	M10X (N.A. 0.25)
M40X (N.A. 0.65)	M100X (N.A. 1.30) oil

Coated eyepieces: P7X, WF10X, P15X, K20X one pair each for binocular observation
Total magnification: 35X to 2,000X
- 4. ILLUMINATION**—Vertical illuminating system with coated plane glass reflector, filter slot, polarizer and analyzer, field and aperture diaphragms, condenser for high and low power, and 6V-30W bulb.
- 5. FOCUSING MECHANISM**
Coarse adjustment: By diagonal-cut rack and pinion, range of vertical movement 55 mm.
Fine adjustment: By micrometer screw and lever, range of vertical movement 2 mm.
- 6. STAGE**—Convenient coaxial control knobs with low drive. Graduated mechanical stage with 24 x 24 mm movement, read-

ing to 0.1 mm by vernier, circular stage plate graduated in degrees (rotatable through 360 degrees) and two additional stage insert plates with apertures of varying sizes.

- 7. CAMERA MECHANISM AND VIEWING SCREEN**
Eyepieces for photography: P10X, P15X, Micro P10X, on revolving turret.
Shutter with speeds: B, T, 1, 1/2, 1/5, 1/10, 1/25, 1/50, sec.
- 8. EXPOSURE METER**—With direct reading system, CdS photocell.
- 9. ADDITIONAL ACCESSORIES**
 1. Polaroid 3 1/4" x 4 1/4" camera back. Polaroid 4" x 5" camera back, 35 mm camera back.
 2. High pressure mercury lamp apparatus.
 3. Xenon lamp apparatus.
 4. Transmitted light apparatus.
 5. Oblique light apparatus.
 6. Dark field light apparatus.
 7. High temperature vacuum heating stage apparatus.
 8. Low power PLAN achromat objectives: MPL 1.3X, MPL 2.5X.
 9. PLAN achromat objectives: MPL 5X, MPL 10X, MPL 20X, MPL 40X, MPL 100X.

MODEL **PMD**



SPECIFICATIONS

- STAND**—Unique, stable, well balanced design and wear-resistant Olympus gray finish. With viewing screen.
- INCLINED BINOCULAR BODY** (30 degrees from horizontal) for either observation or 35 mm camera photography.
- OPTICS**—Four coated, flat field, parfocal achromatic objectives on revolving nosepiece:
M5X (N.A. 0.10) M10X (N.A. 0.25)
M40X (N.A. 0.65) M100X (N.A. 1.30) oil
Coated eyepieces: P7X, WF10X, P15X one pair each for binocular observation.
Total magnification: 35X to 1,500X
- ILLUMINATION**—Vertical illuminating system with coated plane glass reflector, filter slot, polarizer and analyzer, field and aperture diaphragms, condenser for high and low power, and 6V-30W bulb.
- FOCUSING MECHANISM**
Coarse adjustment: By diagonal-cut rack and pinion, range of vertical movement 55 mm.
Fine adjustment: By micrometer screw and lever, range of vertical movement 2 mm.
- STAGE**—Convenient coaxial control knobs with low drive. Graduated mechanical stage with 24 X 24 mm movement, read-

ing to 0.1 mm by vernier, circular stage plate graduated in degrees (rotatable through 360 degrees) and two additional stage insert plates with apertures of varying sizes.

- CAMERA MECHANISM AND VIEWING SCREEN**
Eyepieces for photography: P10X, P15X, Micro P10X, on revolving turret.
Shutter with speeds: B, T, 1, 1/2, 1/5, 1/10, 1/25, 1/50, sec.
- ADDITIONAL ACCESSORIES**
 - Polaroid 3 1/4" x 4 1/4" camera back. Polaroid 4" x 5" camera back, 35mm camera back.
 - High pressure mercury lamp apparatus.
 - Xenon lamp apparatus.
 - Transmitted light apparatus.
 - Oblique light apparatus.
 - Dark field light apparatus.
 - High temperature vacuum heating stage apparatus.
 - Low power PLAN achromat objectives: MPL 1.3X, MPL 2.5X.
 - PLAN achromat objectives: MPL 5X, MPL 10X, MPL 20X, MPL 40X, MPL 100X.
 - Exposure meter for photomicrography Model EMM-V.

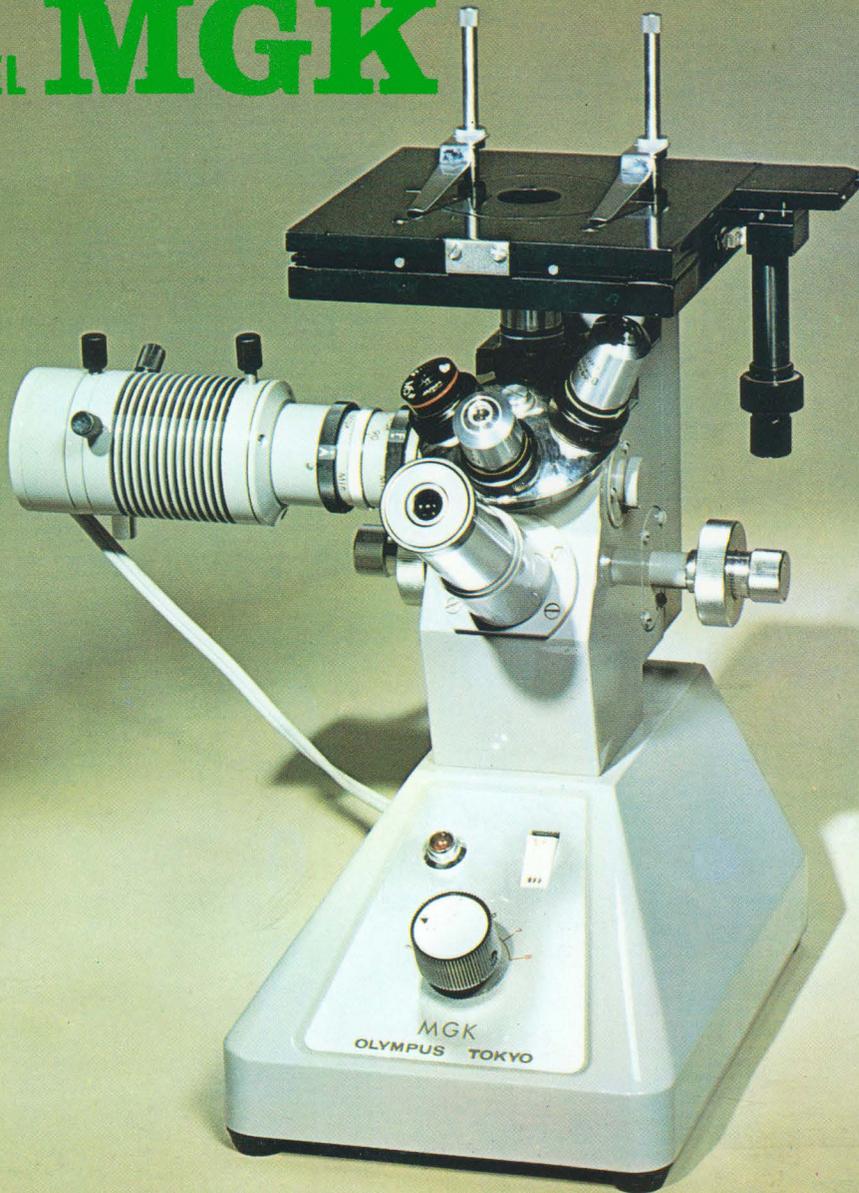
MODEL MG



SPECIFICATIONS

- 1. STAND**—Unique, stable, well balanced design and wear-resistant Olympus gray finish.
- 2. INCLINED BINOCULAR BODY** (30 degrees from horizontal) for either observation or 35 mm camera photography.
- 3. OPTICS**—Four coated, flat field, parfocal achromatic objectives on revolving nosepiece:
M5X (N.A. 0.10) M10X (N.A. 0.25)
M40X (N.A. 0.65) M100X oil (N.A. 1.30)
Coated eyepieces: P7X, WF10X, P15X one pair each for binocular observation
Total magnification: 35X to 1,500X
- 4. ILLUMINATION**—Vertical illuminating system with coated plane glass reflector, filter slot, polarizer and analyzer (built-in), field and aperture diaphragms, and 6V-12W bulb.
- 5. FOCUSING MECHANISM**—Coaxial coarse and fine adjustment system.
Range of vertical movement:
Coarse adjustment 55 mm.
Fine adjustment 2 mm.
Minimum graduation of fine adjustment: 0.005mm
- 6. STAGE**—Convenient coaxial control knobs with low drive. Graduated mechanical stage with 24 x 24 mm movement, reading to 0.1 mm by vernier. Circular stage plate graduated in degrees (rotatable through 360 degrees) and additional two stage insert plates with apertures of varying sizes.
- 7. CAMERA MECHANISM**
Eyepiece for photography: P10X (built-in and fixed).
Shutter with speeds: B, 1, 1/2, 1/5, 1/10, 1/25, 1/50, sec.
- 8. ADDITIONAL ACCESSORIES**
 1. Dry plate photography apparatus.
 2. Polaroid 3 1/4" x 4 1/4" camera back, 35mm camera back.
 3. Transmitted light apparatus.
 4. Oblique light apparatus.
 5. Dark field light apparatus.
 6. Plan achromat objectives: MPL 1.3X, MPL 2.5X, MPL 5X, MPL 10X, MPL 20X, MPL 40X, MPL 100X
 7. Exposure meter for photomicrography Model EMM-V.

MODEL MGK



SPECIFICATIONS

- 1. INCLINED MONOCULAR BODY** (30 degrees from horizontal)
- 2. OPTICS**—Four coated, flat field, parfocal achromat objectives on revolving nosepiece:

M5X (N.A. 0.10)	M10X (N.A. 0.25)
M40X (N.A. 0.65)	M100X oil (N.A. 1.25)

Coated eyepieces: P10X, P15X, one piece each
Total magnification: 50X to 1,500X
- 3. ILLUMINATION**—Vertical illuminating system with coated plane glass reflector, filter slot, field and aperture diaphragms, and 6V-12W bulb. Polarizer and analyzer (built-in).
- 4. FOCUSING MECHANISM**—Coaxial coarse and fine adjustment system.
Range of vertical movement:
Coarse adjustment 55 mm
Fine adjustment 2 mm
Minimum graduation of fine adjustment: 0.005 mm
- 5. STAGE**—Convenient coaxial control knobs with low drive. Mechanical stage with 24 x 24 mm movement. Three stage insert plates with apertures of varying sizes.
- 6. ADDITIONAL ACCESSORIES**
 1. Transmitted light apparatus.
 2. Oblique light apparatus.
 3. Dark field light apparatus.
 4. Plan achromat objectives: MPL 1.3X, MPL 2.5X, MPL 5X, MPL 10X, MPL 20X, MPL 40X, MPL 100X,

OLYMPUS OPTICAL CO., LTD.



3-7, KANDA-OGAWAMACHI CHIYODA-KU,
TOKYO, JAPAN

As we are continually improving and developing our products,
the equipment supplied may not agree in all details with
the descriptions and/or illustrations shown in this catalog.

For further information, please contact with the undermentioned.

Metallurgical Service Laboratories Ltd.

Reliant Works, Brockham
Betchworth, Surrey
England
Telephone: Betchworth 2364